What is claimed is:

1. A microactuator comprising:

a stationary element fixed on a substrate and having a plurality of stationary element electrodes arranged at a predetermined pitch;

a movable element having a plurality of movable element electrodes opposing to said stationary element electrodes, said movable element being moved by applying a voltage across said stationary element and said movable element; and

a first microstructure formed on at least one of opposing surfaces of said movable element and said stationary element to prevent said movable element from attaching to said stationary element.

2. A microactuator according to claim 1, further comprising an insulating film formed on at least one of said opposing surfaces of said movable element and said stationary element, and

wherein said first microstructure is formed on said insulating film.

3. A microactuator according to claim 2, wherein said first microstructure has a microstructural shape formed on a surface of said insulating film.

4. A microactuator according to claim 1, further comprising an insulating film formed on a surface opposing said surface on which said first microstructure is formed.

5. A microactuator according to claim 1, further comprising a second microstructure formed on at least one of opposing surfaces of said movable element and said substrate to prevent said movable element from attaching to said substrate.

6. A microactuator according to claim 5, further comprising an insulating film formed on at least one of said opposing surfaces of said movable element and said substrate, and

wherein said second microstructure is formed on said insulating film.

7. A microactuator according to claim 6, wherein said second microstructure has a microstructural shape formed on a surface of said insulating film.

8. A microactuator comprising:

a stationary element fixed on a substrate and having a plurality of stationary element electrodes formed in a comb tooth shape at a predetermined pitch;

a movable element having a plurality of movable element electrodes separated from a surface of said substrate, formed in a comb tooth shape, and opposing to said stationary element electrodes, said movable element being moved by applying a voltage across said stationary element and said movable element;

a stopper arranged between said movable element and said stationary element to prevent collision of said movable element with said stationary element; and

a microstructure formed on said stopper and at least one of opposing surfaces of one of said movable element and said stationary element which opposes said stopper.

9. A microactuator according to claim 8, wherein said stopper is formed to project from one of said opposing surfaces of said movable element and said stationary element, and

an interval between said stopper and one of said movable element and said stationary element is set smaller than an interval between said movable element and said stationary element.

10. A microactuator according to claim 8, wherein said stopper comprises:

a first engaging member formed on said movable element and projecting toward said stationary element; and

a second engaging member formed on said substrate between said movable element and said stationary element and arranged at a predetermined interval from said first engaging member.

11. A microactuator according to claim 5, wherein at least one of said first and second microstructures has a hemispherical shape, and a top of said hemispherical microstructure contacts said opposing surface.

12. A microactuator according to claim 1, wherein said movable element comprises a plurality of comb tooth portions arranged at a predetermined pitch and each having said movable element electrodes formed on one side,

said stationary element comprises a plurality of comb tooth portions alternately overlapping said comb tooth portions and each having said stationary element electrodes which are formed on one side and oppose said movable element electrodes,

a distal end of each comb tooth portion of said movable element opposes one side of said stationary element, and

a distal end of each comb tooth portion of said stationary element opposes one side of said movable element.

13. A method of manufacturing a microactuator, comprising the steps of:

forming a stationary element having a stationary element electrode and a movable element having a movable element electrode on a semiconductor substrate, said movable element being formed to be separated from a surface of said semiconductor substrate; and

forming a microstructure on said movable element and at least one of opposing surfaces of one of said stationary element and said substrate.

14. A method according to claim 13, wherein the step of forming said microstructure comprises the step of forming a polysilicon thin film on said movable element and at least one of said opposing surfaces of one of said stationary element and said substrate to form a microstructural shape on a surface of said polysilicon thin film.

15. A method according to claim 13, wherein the step of forming said microstructure comprises the step of etching said movable element and at least one of said

opposing surfaces of one of said stationary element and said substrate to form a microstructural shape.